

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

Claims 1 -8 (Canceled)

Claim 9 (Previously Presented): A substrate treating apparatus comprising a processing chamber for processing substrates, and a substrate support member for supporting said substrates in said processing chamber, wherein said substrate support member has multiple holding members installed vertically, each of said holding members has multiple support grooves, each of said support grooves contains a support section to contact said substrate, and a receiving section formed, in a flat plate with a rectangular shape as seen from a plan view, below said support section and extending outwards from a section of the outer periphery of said support section, and said receiving section extends outwards to 6 mm or more from a section of the outer periphery of said support section.

Claims 10 - 18 (Canceled)

Claim 19 (Previously Presented): The substrate treating apparatus according to claim 9, wherein said receiving section extends outwards between 6mm and 15 mm from a section of the outer periphery of said support section.

Claim 20 (Previously Presented): The substrate treating apparatus according to claim 9, wherein said receiving section extends outwards to 10 mm or more from a section of the outer periphery of said support section.

Claim 21 (Previously Presented): The substrate treating apparatus according to claim 9, wherein said receiving section extends outwards between 10 mm and 15 mm from a section of the outer periphery of said support section.

Claim 22 (Currently Amended): The substrate treating apparatus according to claim 9, wherein said ~~receiving~~ support section is formed in a right-angled parallel-piped shape with a rectangular shape as seen from a plan view, and said receiving section is formed in a flat plate with a rectangular shape as seen from a plan view.

Claim 23 (Previously Presented): The substrate treating apparatus according to claim 9, wherein said support section is arranged inside the outer periphery of said receiving section as seen from a plan view.

Claim 24 (Previously Presented): A substrate treating apparatus comprising a processing chamber for processing substrates, and a substrate support member for supporting said substrates in

said processing chamber, wherein said substrate support member has multiple holding members installed vertically, each of said holding members has multiple support grooves, each of said support grooves contains a support section to contact said substrate, and a receiving section, formed in a flat plate with a rectangular shape as seen from a plan view, below said support section and extending outwards from a section of the outer periphery of said support section, said support section is formed in a flat plate with a flat trapezoidal shape as seen from a plan view, and the width of said support section becomes narrower as it approaches the center of said substrate.

Claim 25 (Previously Presented): The substrate treating apparatus according to claim 24, wherein said support section is arranged inside the outer periphery of said receiving section as seen from a plan view.

Claim 26 (Previously Presented): The substrate treating apparatus according to claim 24, wherein each of said holding members has a columnar shape.

Claim 27 (Previously Presented): A substrate treating apparatus comprising a processing chamber for processing substrates, and a substrate support member for supporting said substrates in said processing chamber, wherein said substrate support member has multiple holding members installed vertically, each of said holding members has multiple support grooves, each of said support grooves contains a support section to contact said substrate, and a receiving section, formed as a flat

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plate, below said support section and extending outwards from a section of the outer periphery of said support section, said support section is formed in a flat plate with a trapezoidal shape as seen from a plan view, and the width of said support section becomes narrower as it approaches the center of said substrate.

Claim 28 (Previously Presented): The substrate treating apparatus according to claim 27, wherein said support section is arranged inside the outer periphery of said receiving section as seen from a plan view.

Claim 29 (Previously Presented): The substrate treating apparatus according to claim 27, wherein each of said holding members has a columnar shape.